

IN THE CLAIMS:

1-15 (cancelled).

16. (original) A mobile system for preconditioning a semiconductor processing chamber having an upper chamber and a lower chamber, comprising:

a mobile cart;

a hot gas recirculating system coupled to the mobile cart and adapted to couple to the upper chamber;

a vacuum source coupled to the cart and adapted to couple to the upper chamber;

a leak rate testing source coupled to the cart and adapted to couple to the upper chamber; and

a particle count testing source coupled to the cart and adapted to couple to the upper chamber.

17. (original) The system of Claim 16, wherein the mobile cart comprises:

a base; and

a support plate coupled to the base for supporting the upper chamber of the processing chamber.

18. (original) The system of Claim 17, and further comprising:

a vibration isolation system disposed between the base and the support plate;

at least one wheel coupled to the base;

at least one handle coupled to the base; and

a chamber cover coupled to the base.

19. (original) The system of Claim 17, and further comprising a heating system coupled to the support plate for heating the upper chamber.

20. (original) The system of Claim 16, wherein the hot gas recirculating system is operable to cycle purge hot nitrogen gas through the upper chamber.

21. (original) The system of Claim 20, and wherein the hot gas recirculating system comprises:

- an inlet valve operable to receive hot nitrogen gas;

- an inlet bellows coupled to the inlet valve and operable to transport the hot nitrogen gas to the upper chamber;

- an outlet bellows operatively coupled to the upper chamber and operable to transport the hot nitrogen gas away from the upper chamber; and

- an outlet valve coupled to the outlet bellows and operable to relinquish the hot nitrogen gas.